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US 20060037187 A1	20060223	PROCESS OF MAKING A MICROTUBE AND MICROFLUIDIC DEVICES FORMED THEREWITH	29/592.1	73/204.26; 73/861.351	Sparks; Douglas Ray et al.
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US 20040255648 A1	20041223	RESONANT TUBE VISCOSITY SENSING DEVICE	73/54.41		Sparks, Douglas Ray
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